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PATENT APPLICATION

ASSISTANT COMMISSIONER FOR PATENTS

Washington, D. C. 20231

Atty. Docket No. AM2119/T21300

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Assistant Commissioner for Patents
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By

Sir:

Transmitted herewith for filing is the

☒ patent application

☐ design patent application

☐ continuation-in-part patent

application of

Inventor(s): KARL A. LITTAU, CHILIANG L. CHEN, and ANAND VASUDEV

For: REMOTE PLASMA CLEANING SOURCE HAVING REDUCED REACTIVITY WITH A SUBSTRATE PROCESSING CHAMBER

☐ This application claims priority from each of the following Application Nos./filing dates:

Enclosed are:

☒ Fourteen (14) sheet(s) of ☐ formal ☒ informal drawing(s).

☒ A ☐ signed ☒ unsigned Declaration & Power of Attorney.

☒ Information Disclosure Statement under 37 CFR 1.97.

☒ Form PTO-1449 (1 page)

☒ Copies of 13 references cited on the Form PTO-1449

In view of the unsigned Declaration as filed with this application, and pursuant to 37 CFR §1.53(d), Applicant requests deferral of the filing fee until submission of the Missing Parts of Application.

Please do not charge the filing fee at this time.

One extra copy of this sheet is enclosed.

Respectfully submitted,
TOWNSEND and TOWNSEND and CREW LLP

Kenneth C. Brooks

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